



dfw

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of : **Confirmation No. 4044**
Akihisa HONGO et al. : Docket No. 2003_1822A
Serial No. 10/735,771 : Group Art Unit 1765
Filed December 16, 2003 : Examiner Eric Brice Chen

SUBSTRATE PROCESSING APPARATUS
AND SUBSTRATE PROCESSING METHOD

THE COMMISSIONER IS AUTHORIZED
TO CHARGE ANY DEFICIENCY IN THE
FEES FOR THIS PAPER TO DEPOSIT
ACCOUNT NO. 23-0975

RESPONSE TO RESTRICTION REQUIREMENT

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

In response to the Restriction Requirement of August 9, 2005, Applicants hereby elect Group I, which is drawn to an apparatus and is embodied by claims 1-9 and 16-33, without traverse.

Having made the required election, a full examination on the merits of the elected group is requested.

Respectfully submitted,

Akihisa HONGO et al.

By: Michael S. Huppert
Michael S. Huppert
Registration No. 40,268
Attorney for Applicants

MSH/kjf
Washington, D.C. 20006-1021
Telephone (202) 721-8200
Facsimile (202) 721-8250
September 7, 2005